



Docket No.: 060188-0578

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 53080
Shinichi IMAI, et al.	:	Confirmation Number: 4939
Application No.: 10/619,191	:	Group Art Unit: 2125
Filed: July 15, 2003	:	Examiner: Maria N. Von Buhr

For: SYSTEM AND METHOD FOR MONITORING SEMICONDUCTOR PRODUCTION APPARATUS

AMENDMENT FILED WITH RCE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following amendment and remarks are submitted in response to the Final Official Action mailed January 12, 2007, having a three-month shortened statutory period for reply set to expire on April 12, 2007, a petition for a one month extension of time up to and including May 12, 2007 being filed concurrently herewith, please amend the above identified application as follows.

Amendments to the Claims begin on page 2.

Remarks begin on page 6.